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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/783,057	02/20/2004	Tadayuki Fujiwara	NGB-15369	6775
40854 7590 12/04/2007 RANKIN, HILL, PORTER & CLARK LLP 38210 Glenn Avenue WILLOUGHBY, OH 44094-7808			EXAMINER SUGLO, JANET L	
			ART UNIT 2857	PAPER NUMBER
			MAIL DATE 12/04/2007	DELIVERY MODE PAPER

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

Office Action Summary	Application No. 10/783,057	Applicant(s) FUJIWARA ET AL.	
	Examiner Janet Suglo	Art Unit 2857	

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☒ Responsive to communication(s) filed on 18 April 2007.
- 2a) ☐ This action is **FINAL**. 2b) ☒ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 1-5 is/are pending in the application.
- 4a) Of the above claim(s) _____ is/are withdrawn from consideration.
- 5) ☐ Claim(s) _____ is/are allowed.
- 6) ☒ Claim(s) 1-5 is/are rejected.
- 7) ☐ Claim(s) _____ is/are objected to.
- 8) ☐ Claim(s) _____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☒ The drawing(s) filed on 30 April 2004 is/are: a) ☒ accepted or b) ☐ objected to by the Examiner.
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) ☒ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☒ All b) ☐ Some * c) ☐ None of:
1. ☒ Certified copies of the priority documents have been received.
 2. ☐ Certified copies of the priority documents have been received in Application No. _____.
 3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).
- * See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- | | |
|-----------------------------------------------------------------------------------------------------------------------|-----------------------------------------------------------------------------------------|
| 1) <input checked="" type="checkbox"/> Notice of References Cited (PTO-892) | 4) <input type="checkbox"/> Interview Summary (PTO-413)
Paper No(s)/Mail Date. _____ |
| 2) <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948) | 5) <input type="checkbox"/> Notice of Informal Patent Application |
| 3) <input checked="" type="checkbox"/> Information Disclosure Statement(s) (PTO/SB/08)
Paper No(s)/Mail Date _____ | 6) <input type="checkbox"/> Other: _____ |

DETAILED ACTION

Claim Rejections - 35 USC § 112

1. The following is a quotation of the second paragraph of 35 U.S.C. 112:

The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.

2. **Claims 1-6** are rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention. In claim 1, line 10, and in claim 4, line 9, Applicant claims "a redetermination of at least one of a panel and a substrate based on the defect information." It is unclear how a panel or a substrate could be redetermined or even determined. Based on the specification, it appears that the Applicant is intending to claim that the *defect information* or defective state of the panel or substrate is being redetermined and the claims will be examined based upon this understanding.
3. **Claims 1-6** rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention. Claim 1, lines 4-8 and claim 4, lines 3-5 state "a database for recording a defect information acquired from a liquid crystal testing device, and an image information and a repair information including a defect repaired information which are acquired from a liquid crystal repair device." It is unclear whether the image information and repair information are included in the database or only acquired from a liquid crystal repair device. It is further unclear what information includes the defect repaired information and which information is acquired from a liquid crystal repair

device. For the purposes of this office action, the claim language will be interpreted to mean that the image information and repair information are stored in the database.

Further it will be interpreted to mean that the repair information alone includes the defect repaired information, and that the defect repair information is the only information acquired from the liquid crystal repair device.

Claim Rejections - 35 USC § 102

4. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

(a) the invention was known or used by others in this country, or patented or described in a printed publication in this or a foreign country, before the invention thereof by the applicant for a patent.

5. **Claims 1 and 4** are rejected under 35 U.S.C. 102(a) as being anticipated by Lee et al. (US Patent 6,473,664) (hereinafter "Lee").

With respect to **claim 1**, Lee teaches an apparatus for managing a liquid crystal substrate (col 1, ln 10-12) comprising:

a data management section having a database for recording a defect information acquired from a liquid crystal testing device (e.g., Host, File Server) (Figure 4: 100, 110; col 9, ln 55-65), and an image information (col 5, ln 20-25) and a repair information (col 5, ln 50-55) including a defect repaired information which are acquired from a liquid crystal repair device (col 5, ln 50-55), said data management section performing at least one of a reidentification of a defect and a redetermination of at least one of a panel and

a substrate based on the defect information (col 10, ln 1-16), the image information and the repair information recorded in said database (Figure 4: 100, 110; col 5, ln 50-55, col 9, ln 55-65).

With respect to **claim 4**, Lee teaches a method for managing a liquid crystal substrate (col 1, ln 10-12) comprising:

recording a defect information acquired from a liquid crystal testing device (Figure 4: 100, 110; col 9, ln 55-65), and an image information (col 5, ln 20-25) and a repair information (col 5, ln 50-55) including a defect repaired information which are acquired from a liquid crystal repair device in a database (col 5, ln 50-55); and

performing at least one of a reidentification of a defect and a redetermination of at least one of a panel and a substrate based on the defect information (col 10, ln 1-16), the image information and the repair information recorded in the database (Figure 4: 100, 110; col 5, ln 50-55, col 9, ln 55-65).

Claim Rejections - 35 USC § 103

6. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

7. **Claims 2, 3 and 5** are rejected under 35 U.S.C. 103(a) as being unpatentable over Lee in view of Miura et al. (US Patent 6,282,457) (hereinafter "Miura").

With respect to **claim 2**, Lee further teaches said data management section stores a recipe information for defining specifications of the substrate and panel in said database (Lee: col 8, ln 64 - col 9, ln 6). Lee further teaches that the user inputs necessary data when data is processed abnormally (Lee: col 10, ln 17-20). Lee does not specify that said recipe information is edited freely. Miura teaches a method and apparatus for processing liquid crystal panel substrates (Miura: col 13, ln 20-22) including adjusting or finely modifying the recipes. It would have been obvious to one of ordinary skill in the art at the time of the invention to modify Lee to include the recipe modifications of Miura because this ensures an optimal exposure recipe resulting in more efficient processing (Miura: col 2, ln 59-62; col 12, ln 46-47).

With respect to **claim 3**, Lee further teaches a terminal connected to the data management system where a user can input information (Lee: col 10, ln 17-20). Lee does not teach that the data management section edits the recipe information by exchange of information with the terminal. Miura teaches a method and apparatus for processing liquid crystal panel substrates (Miura: col 13, ln 20-22) including adjusting or finely modifying the recipes. It would have been obvious to one of ordinary skill in the art at the time of the invention to modify Lee to include the recipe modifications of Miura because this ensures an optimal exposure recipe resulting in more efficient processing (Miura: col 2, ln 59-62; col 12, ln 46-47).

With respect to **claim 5**, Lee further teaches recording a recipe information acquired from the liquid crystal testing device in the database, the recipe information defining specifications of the substrate and panel (Lee: col 8, ln 64 - col 9, ln 6). Lee

further teaches that the user inputs necessary data when data is processed abnormally (Lee: col 10, ln 17-20). Miura teaches a method and apparatus for processing liquid crystal panel substrates (Miura: col 13, ln 20-22) including adjusting or finely modifying the recipes. It would have been obvious to one of ordinary skill in the art at the time of the invention to modify Lee to include the recipe modifications of Miura because this ensures an optimal exposure recipe resulting in more efficient processing (Miura: col 2, ln 59-62; col 12, ln 46-47).

Conclusion

8. The prior art made of record and not relied upon is considered pertinent to applicant's disclosure.

Karasawa (US Patent 7,133,807) teaches an apparatus for productivity improving including monitoring processing system remotely.

Takagi et al. (US Patent 6,438,438, US PGPub 2001/0020194) teaches a method and system for manufacturing semiconductor devices and inspecting those devices.

Todate et al. (US Patent 6,269,279) teaches a control system for a processing sytem.

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Any inquiry concerning this communication or earlier communications from the examiner should be directed to Janet Suglo whose telephone number is 571-272-8584. The examiner can normally be reached on Monday - Thursday from 6:30am - 5:00pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Eliseo Ramos-Feliciano can be reached on 571-272-7925. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

Janet L Suglo
November 29, 2007


ELISEO RAMOS-FELICIANO
SUPERVISORY PATENT EXAMINER 11/29/07